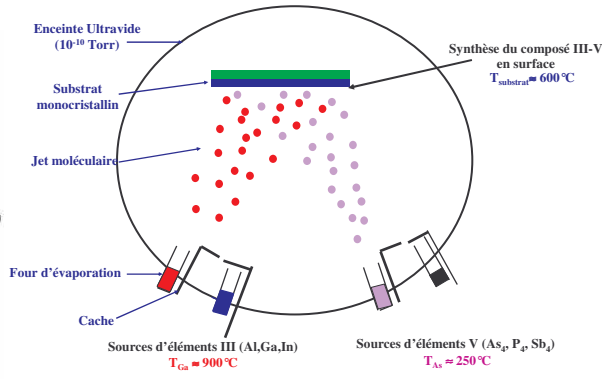
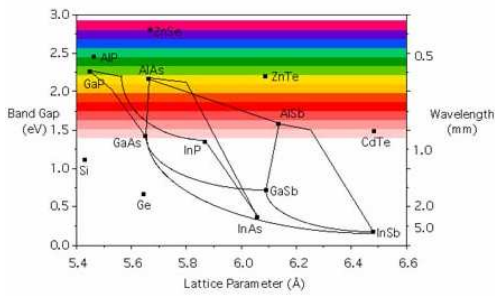


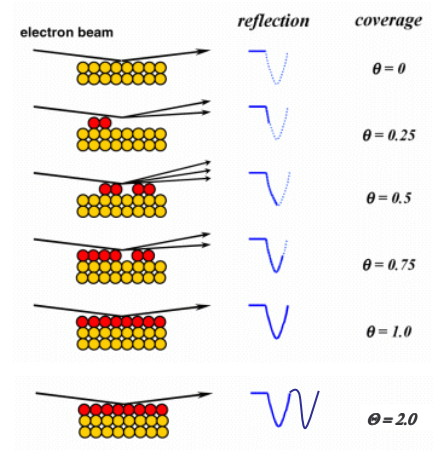
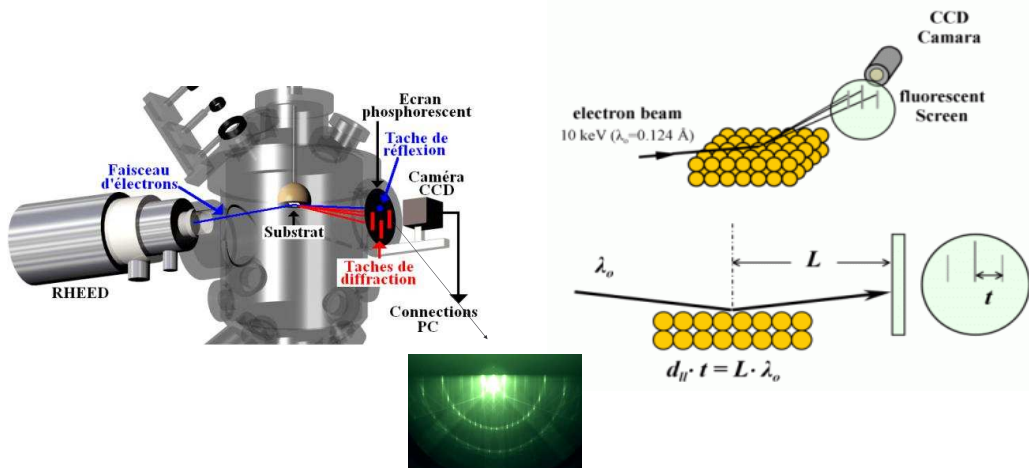
Méthode de croissance cristalline de couches nanométriques

Principe

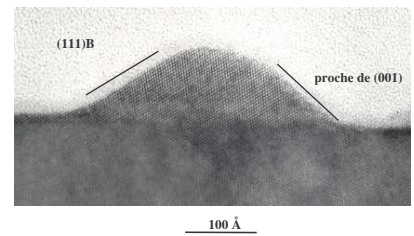
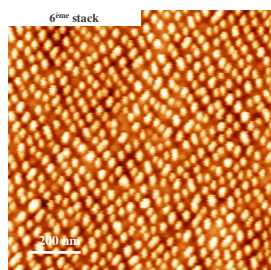
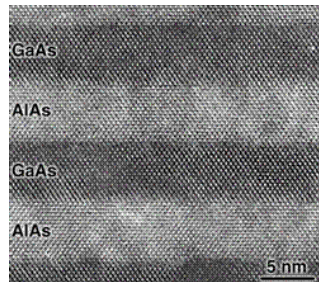
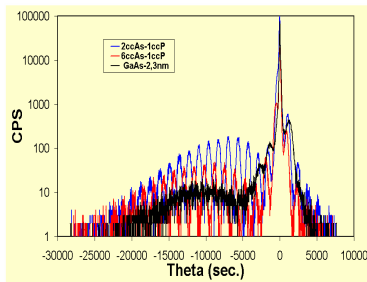
Band Gap versus Lattice Parameter for IV, III-V, and II-VI Semiconductors



Contrôle *In situ* : RHEED



Contrôle *ex situ* : RX, AFM, X-STM, TEM



Caractérisation de puits quantiques et super-réseaux

Caractérisation des Boîtes quantiques InAs/GaInAsP/InP(311)B

